

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	3	sensor with (metal\$4 adj (film or layer)) with (dielectric adj (film or layer))	JPO	OR	ON	2005/04/18 07:52
S1	4495	29/417,592.1,595,831,846.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:12
S2	1229	156/73.1.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/01/24 15:10
S4	755	427/79,80.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:17
S5	446	216/65.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:14
S57	5582	29/417,592.1,595,609,831,846.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:13
S58	2887	216/22,39,41,48.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:14
S59	514	electromechanical adj sensor	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:17
S61	9949	(metal\$4 adj (film or layer)) with (dielectric adj (film or layer))	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:26
S62	0	S59 and S61	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:17
S63	6	S59 and "361"/\$.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:19
S64	0	S57 and S59	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:19
S65	0	S59 and (laminat\$3 with metal\$4 with dielectric)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:20
S66	6	((("5961762") or ("4874659") or ("4654546")).PN.	USPAT; USOCR; JPO; DERWENT	OR	OFF	2005/04/15 11:20

S67	22	("3632443"   "3671784"   "3736436"   "3832580"   "3894243"   "3921014"   "3943614"   "3947644"   "3971250"   "4096756"   "4160883"   "4186323"   "4291244"   "4291245"   "4322877"   "4340786"   "4354132"   "4369391"   "4370182"   "4397702"   "4451710"   "4491760").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/04/15 11:22
S68	27	("4654546").URPN.	USPAT	OR	ON	2005/04/15 11:24
S69	89	sensor with (metal\$4 adj (film or layer)) with (dielectric adj (film or layer))	USPAT; JPO; DERWENT	OR	ON	2005/04/18 07:52
S70	0	S57 and S69	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:26
S71	547	laminat\$3 with (metal\$4 adj (film or layer)) with (dielectric adj (film or layer))	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:30
S72	4	S69 and S71	USPAT; JPO; DERWENT	OR	ON	2005/04/15 11:27
S73	6	("4370182").URPN.	USPAT	OR	ON	2005/04/15 11:28
S74	15	("4460427").URPN.	USPAT	OR	ON	2005/04/15 11:30
S75	206	(dielectric near pattern) with electrode	USPAT	OR	ON	2005/04/15 11:31
S76	14	S61 and S75	USPAT	OR	ON	2005/04/15 11:31
S77	3	S76 and roll\$3	USPAT	OR	ON	2005/04/15 11:31
S78	3129	310/311,314,317,344.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:16
S79	1	S59 and S78	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:16
S80	645	381/114,116,191.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:16
S81	0	S59 and S80	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:16
S82	3562	electromechanical with sensor	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:17
S83	1	S80 and S82	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:17

S84	5625	156/164,229,273.1,273.3,273.9, 274.6,308.2,322,324.ccls.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:18
S85	0	S82 and S84	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:18
S86	2	S71 and S84	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:20
S87	3	Raisanen-Heikki.in.	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:21
S88	0	sensor with (metal\$4 adj (film or layer)) with (dielectric adj (film or layer)) with roller	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:44
S89	0	laminat\$3 with (dielectric adj pattern) with (metal adj (layer or film))	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:32
S90	5	laminat\$3 with (dielectric near pattern) with (metal adj (layer or film))	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:31
S91	0	laminat\$3 with (dielectric near pattern) with (metal adj (layer or film)) same roll\$3	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:31
S92	21	(dielectric adj pattern) with (metal adj (layer or film))	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:33
S93	2	S92 and roll\$3	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:32
S94	46	print\$3 with (dielectric adj pattern)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:49
S95	2	print\$3 with (dielectric adj pattern) same roll\$3	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:36
S96	7	print\$3 same (dielectric adj pattern) same roll\$3	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:36
S97	8	(dielectric adj pattern) same roll\$3	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:43
S98	32160	roll\$3 with laminat\$3	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:43
S99	3858	roll\$3 adj laminat\$3	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:43

S10 0	9949	(metal\$4 adj (film or layer)) with (dielectric adj (film or layer))	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:44
S10 1	35	S99 and S100	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:46
S10 2	17630	roll near roll	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:46
S10 3	1015	roll-to-roll	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:46
S10 4	7	S100 and S103	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:46
S10 5	353	(print\$3 or coat\$3 or sputter\$3 or form\$3) with (dielectric adj pattern)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:50
S10 6	0	S103 and S105	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:50
S10 7	0	(print\$3 or coat\$3 or sputter\$3 or form\$3) with (dielectric adj pattern) same roll-to-roll	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:50
S10 8	0	(print\$3 or coat\$3 or sputter\$3 or form\$3) with (dielectric adj pattern) same (roll-to-roll)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:50
S10 9	0	((print\$3 or coat\$3 or sputter\$3 or form\$3) with (dielectric adj pattern)) and (roll-to-roll)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:50
S11 0	0	(dielectric adj pattern) with (roll-to-roll)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:51
S11 1	0	(dielectric near pattern) with (roll-to-roll)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:51
S11 2	0	(print\$3 near pattern) with (roll-to-roll)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:51
S11 3	4	(print\$3 near pattern) same (roll-to-roll)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:52
S11 4	88	S84 and (print\$3 near pattern)	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:53
S11 5	0	S100 and S114	USPAT; JPO; DERWENT	OR	ON	2005/04/15 12:53


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| <input type="checkbox"/> | <p>5. Analog-digital wide-range measurement systems with adaptively adjusted quartz glass sensors<br/>Szabatin, J.; Melnikov, V.E.; Platonov, A.A.;<br/>Instrumentation and Measurement Technology Conference, 1996. IMTC-96. Conference Proceedings. 'Qualit<br/>Indispensable Bridge between Theory and Reality', IEEE<br/>Volume 2, 1996 Page(s):1154 - 1159 vol.2<br/><br/><a href="#">AbstractPlus</a>   Full Text: <a href="#">PDE(568 KB)</a> IEE CNF</p> |
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